



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : LAERMER et al. Confirmation No.: 5642
 Serial No. : 09/720,761
 Filed : March 26, 2001
 For : METHOD OF PLASMA ETCHING OF SILICON
 Examiner : K. Chen
 Art Unit : 1765
 Customer No. : 26646

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O.K to enter

AMENDMENT

KCC 9/3/06

SIR:

As a supplemental response to the final Office Action dated February 22, 2006, and as a response to the Advisory Action mailed on June 7, 2006, please amend the above-captioned application as follows.

Amendments to the Specification do not appear in this paper.

Amendments to the Claims are found in the listing of the claims which begins on page 2 of this paper.

Amendments to the Drawings do not appear in this paper

Remarks begin on page 4 of this paper.

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